

Spintronics Nanodevice

- How small can we make it and what else can we use it for -

Hideo Ohno¹⁻⁵

President, Tohoku University

¹Laboratory for Nanoelectronics and Spintronics,

Research Institute of Electrical Communication, Tohoku University

²Center for Science and Innovation in Spintronics, Tohoku University

³Center for Spintronics Research Network, Tohoku University

⁴Center for Innovative Integrated Electronic Systems, Tohoku University

⁵WPI Advanced Institute for Materials Research, Tohoku University

**Collaborators: S. Fukami, K. Watanabe, B. Jinnai, A. Kurenkov, W. A. Borders, T. Hanyu, T. Endoh,
the CSIS team, and the team led by Supriyo Datta**

Work supported in part by the ImPACT Program of CSTI, by the R&D Project for ICT Key Technology of MEXT,
JST-OPERA, and by Grant-in-Aid for Specially Promoted Research (17H06093)



- 1. What spintronics delivers**
- 2. Scaling further**
- 3. Can you do more**

Current Working Memories

DRAM: dense, $6F^2$

SRAM: fast, $200F^2$

Volatile

Energy Consumption & Carbon Footprint of the IT Sector



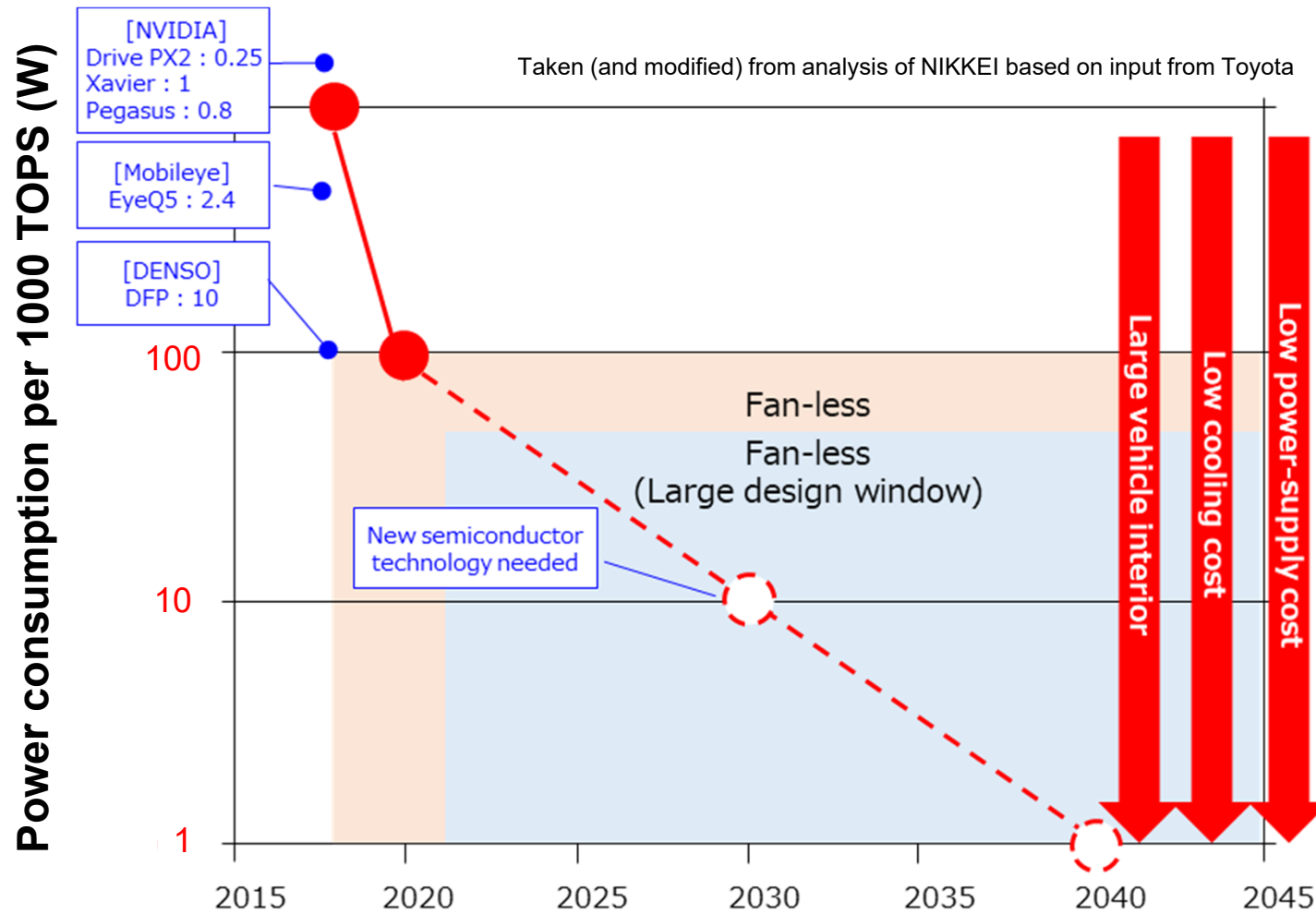
Wednesday, July 18, 2018

Internet-connected devices produce 3.5% of global emissions within 10 years and 14% by 2040. (Source: [Climate Home News](#))

Communications industry responsible for 20% of all the world's electricity in 2025. (Source: [The Guardian](#))

Data centers consume 1/5 of Earth's power in 2025. (Source: [Data Economy](#)).

AI chip requirement for autonomous driving





<http://archive.doobybrain.com/2013/09/03/office-building-lights-night/>

Announcements of STT-MRAM 2017-2018

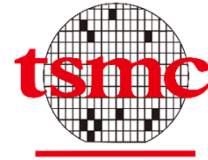


Samsung ready to mass produce MRAM chips

28nm FD-SOI process

Samsung Foundry will soon be ready to enter mass production of magnetoresistive random-access memory (MRAM) chips built using 28nm fully depleted silicon-on-insulator (FD-SOI) process technology, according to Korea media reports.

Digitimes, 26 Sep. 2017.



TSMC to start eMRAM production in 2018

22 nm process

According to reports, TSMC is aiming to start producing embedded MRAM chips in 2018, "aiming to start producing embedded MRAM chips in 2018" to gauge market reception.

MRAM-info, 8 Jun. 2017.



GLOBALFOUNDRIES Announces Availability of Embedded MRAM on Leading 22FDX® FD-SOI Platform

Sep 20, 2017

Advanced embedded non-volatile

22nm FD-SOI

the 22nm process node

Santa Clara, Calif., September

memory (eMRAM) technology

embedded magnetoresistive non-volatile

embedded memory solution, GF's

22FDX eMRAM provides high performance and superior reliability for broad applications in consumer and industrial controllers, data centers, Internet of Things (IoT), and automotive.

GLOBALFOUNDRIES press release, 20 Sep. 2017.



Intel says its embedded 22nm MRAM is production ready

22nm FinFET CMOS

In October, Intel

integrated

the company has successfully produced 22nm MRAM wafers.

MRAM-info, 20 Feb. 2019.

MTJ Size ~ several 10 nm

Papers presented at IEDM2019



Demonstration of a Reliable 1 Gb Standalone Spin-Transfer Torque MRAM For Industrial Applications



1Gbit High Density Embedded STT-MRAM
in 28nm FDSOI Technology



Manufacturable 22nm FD-SOI Embedded MRAM Technology for Industrial-grade MCU and IOT Applications



2 MB Array-Level Demonstration of STT-MRAM Process and Performance Towards L4 Cache Applications

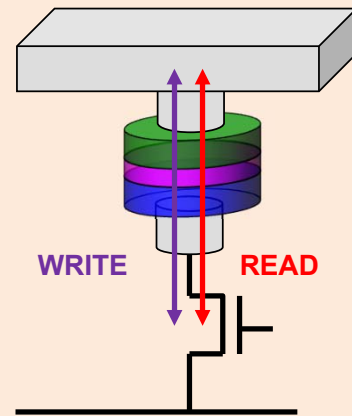


22nm STT-MRAM for Reflow and Automotive Uses with High Yield, Reliability, and Magnetic Immunity and with Performance and Shielding Options

Nonvolatile spintronic device - Magnetic Tunnel Junction -

Structure

Two-terminal



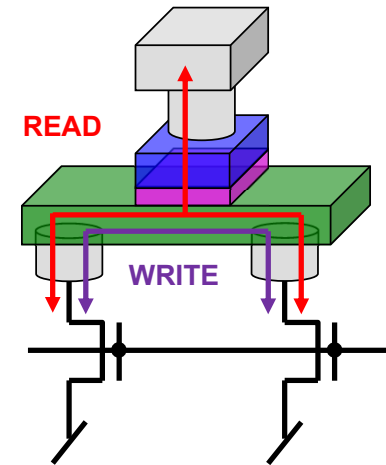
Application

- Large capacity

Switching

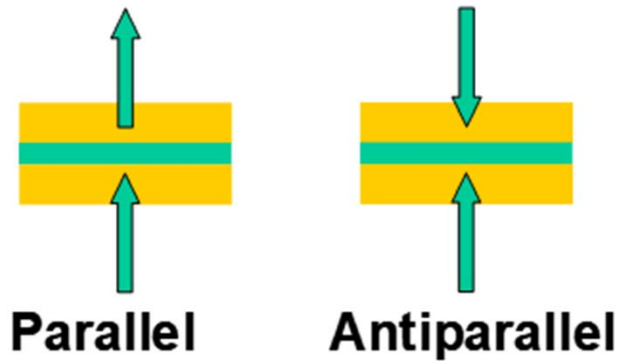
- **Spin-transfer torque (STT)**
- Electric field

Three-terminal



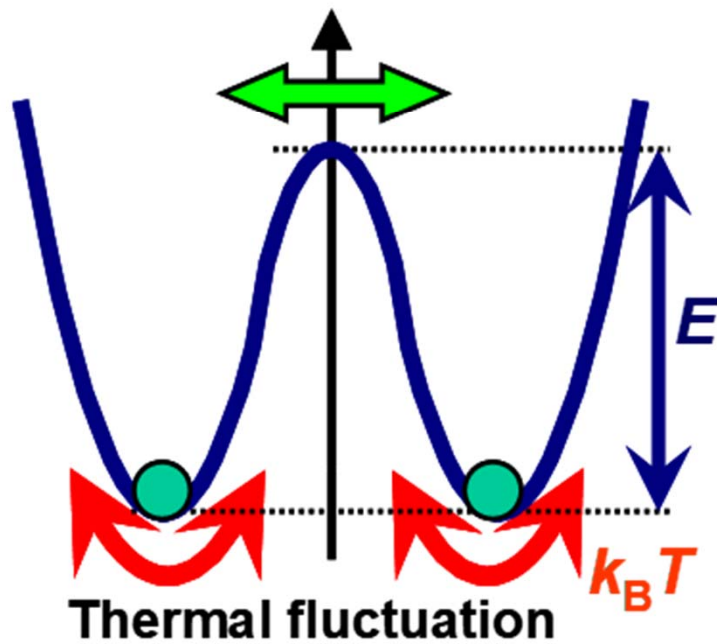
- High-speed, high-reliability

- Current-induced DW motion
- **Spin-orbit torque (SOT)**



$$\tau = \tau_0 e^{E/k_B T}$$

$$E/k_B T > 80$$



Perpendicular to the plane

Switching efficiency

Footprint

Energy barrier E

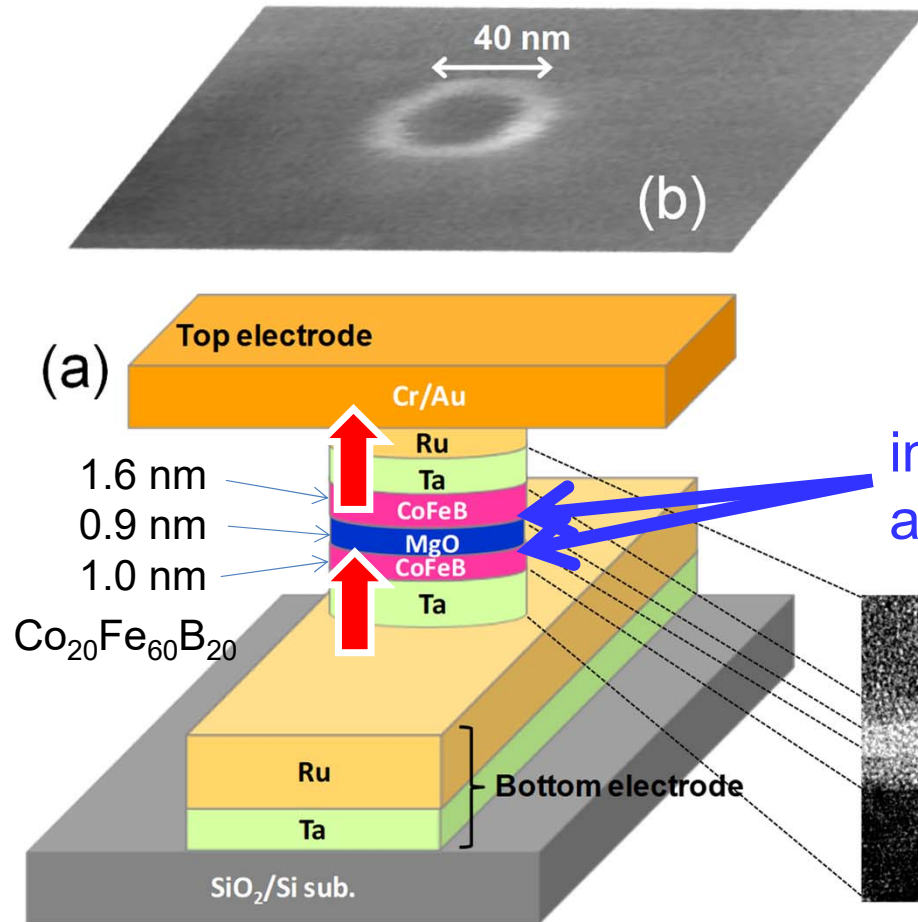
$$E = \underbrace{N}_{\text{shape anisotropy}} \frac{M_S^2}{2\mu_0} V + K_i S$$

shape anisotropy

interface anisotropy

V: volume
S: area

Perpendicular MgO-CoFeB Magnetic Tunnel Junction



$$J_{C0} = 3.8 \text{ MA/cm}^2$$

$$(I_{C0} = 48 \text{ } \mu\text{A})$$

$$E/k_B T \sim 40$$

$$\text{TMR ratio} = 110\%$$

$$T_a = 350^\circ\text{C} \text{ now } > 400^\circ\text{C}$$

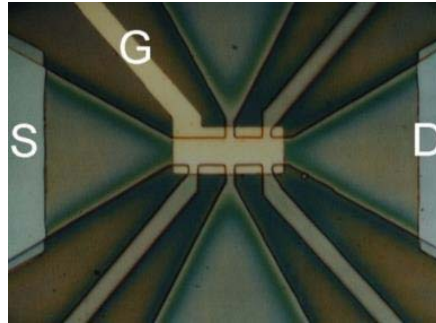
interface perpendicular
anisotropy

$$E = -\frac{M_S^2}{2\mu_0} V + K_i S$$

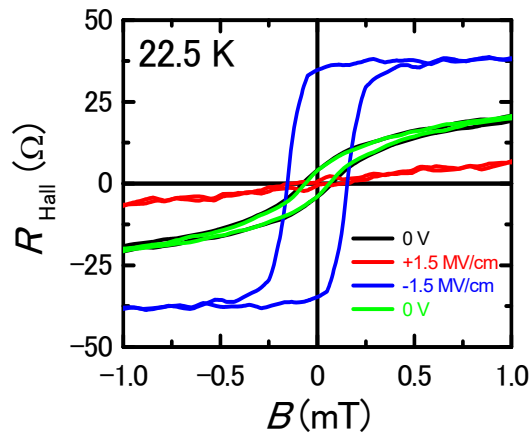
S. Ikeda et al., *Nature Mat.* **9**, 721 (2010)

Electric-field control of magnets

Ferromagnetic transition and coercivity

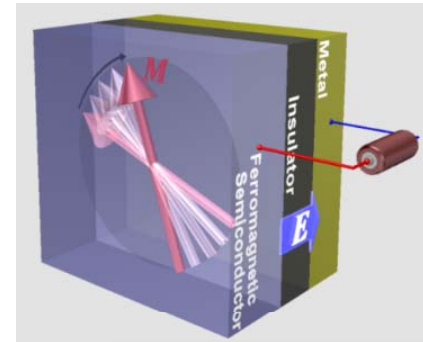


Ferromagnetic semiconductor (In,Mn)As

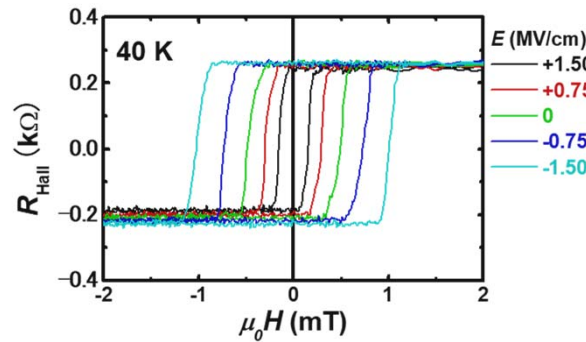


H. Ohno *et al.*, *Nature* 408, 944 (2000)

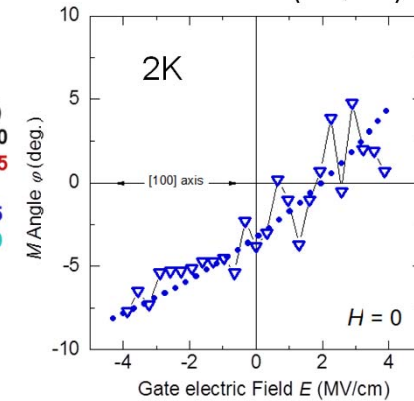
Magnetization direction



Ferromagnetic Semiconductor (Ga,Mn)As

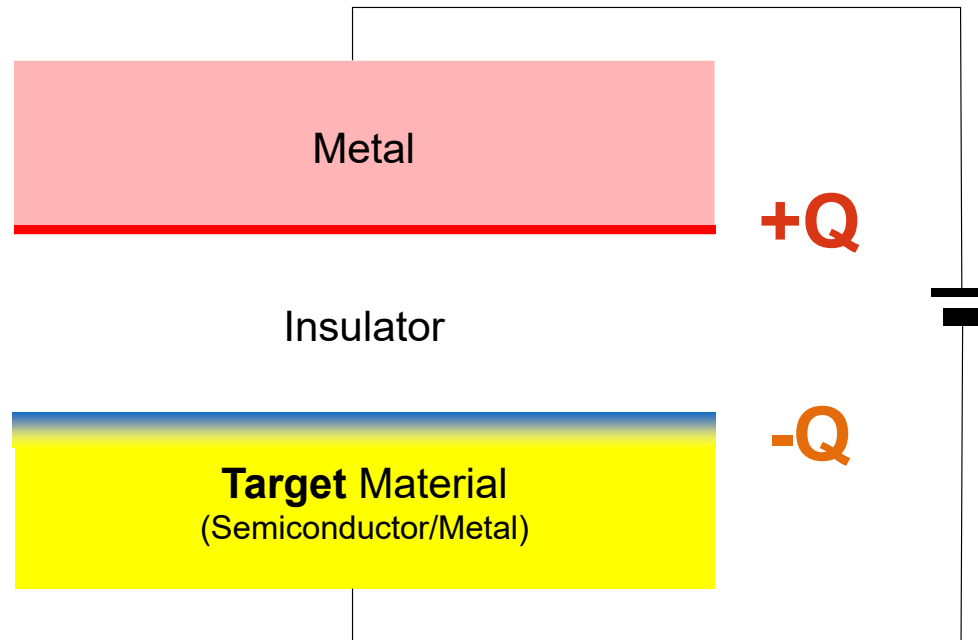


D. Chiba *et al.*, *Science* 301, 943 (2003)

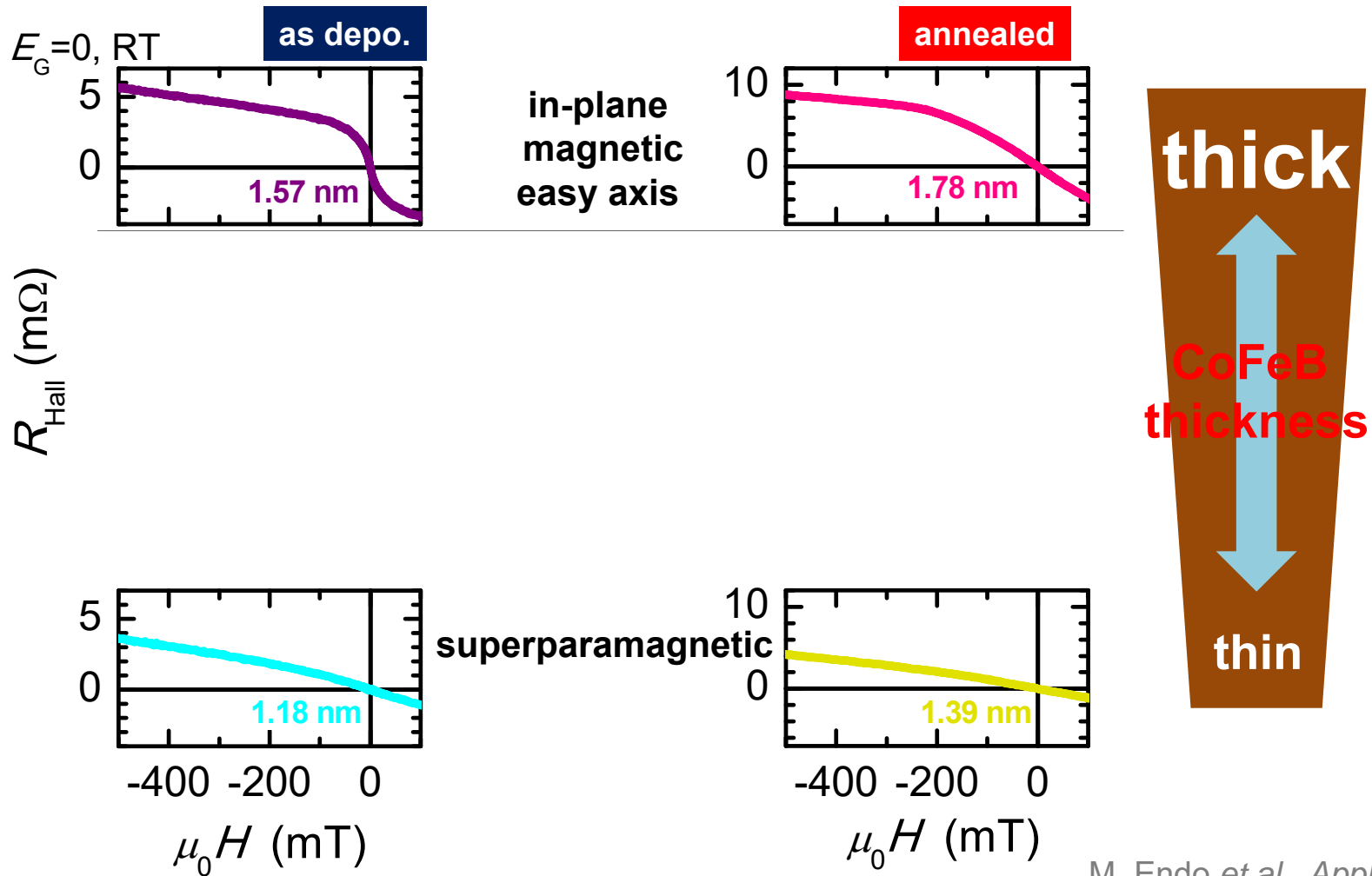


D. Chiba *et al.*, *Nature* 455, 515 (2008)

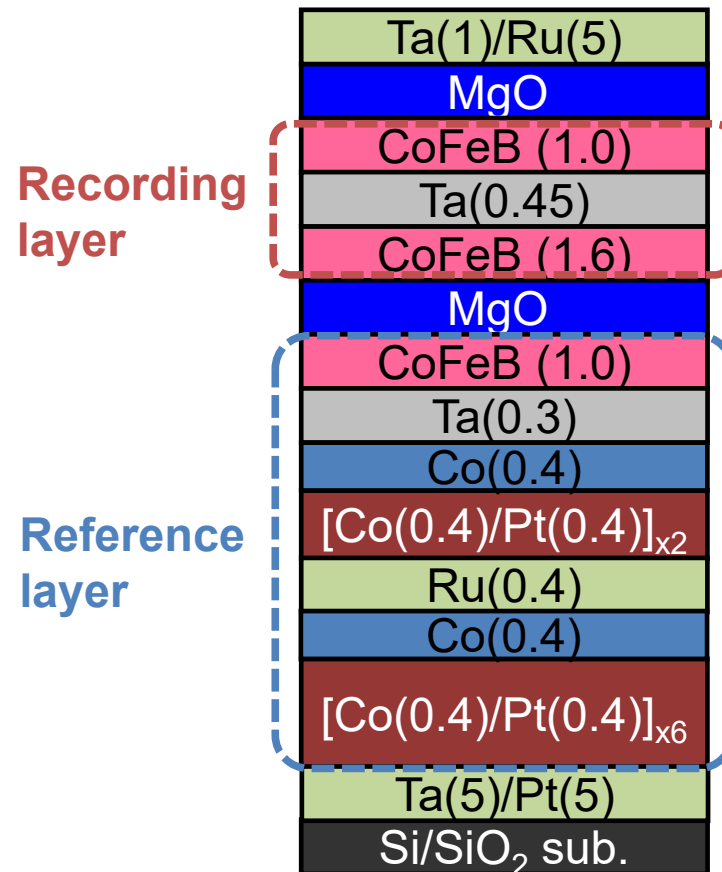
Electric-field control



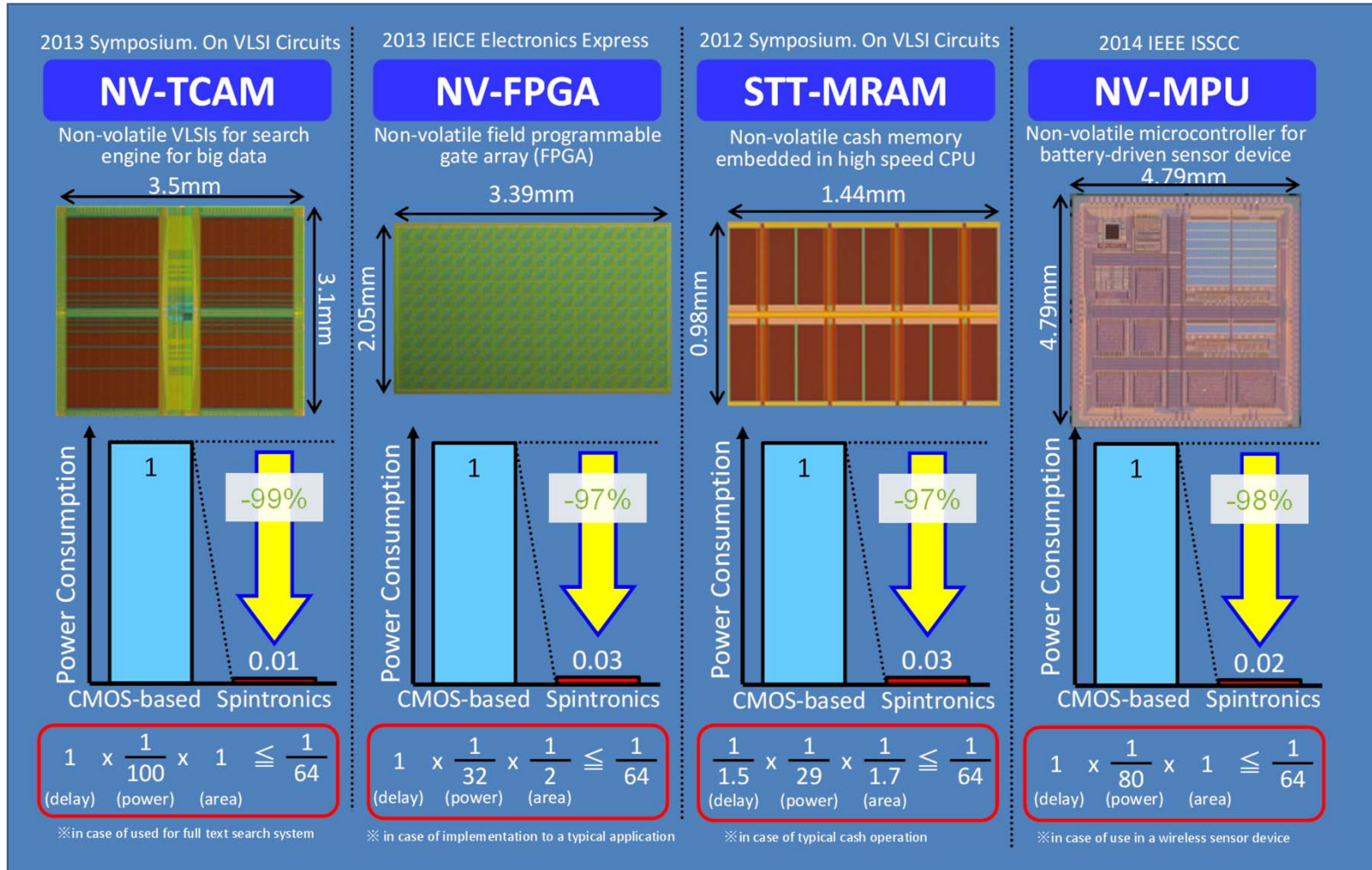
Thickness dependence of anisotropy in CoFeB/MgO



Double CoFeB-MgO interface structure



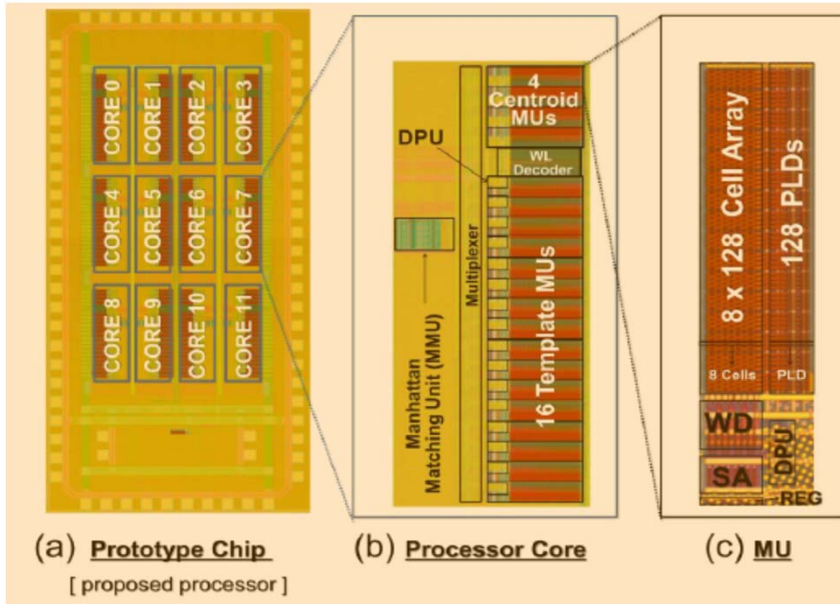
MTJ/CMOS Low Power VLSIs



Prototype on 300 mm by Tohoku University

AI Processor by CMOS/MTJ VLSI

Associative processor includes **12 core unit processor**.



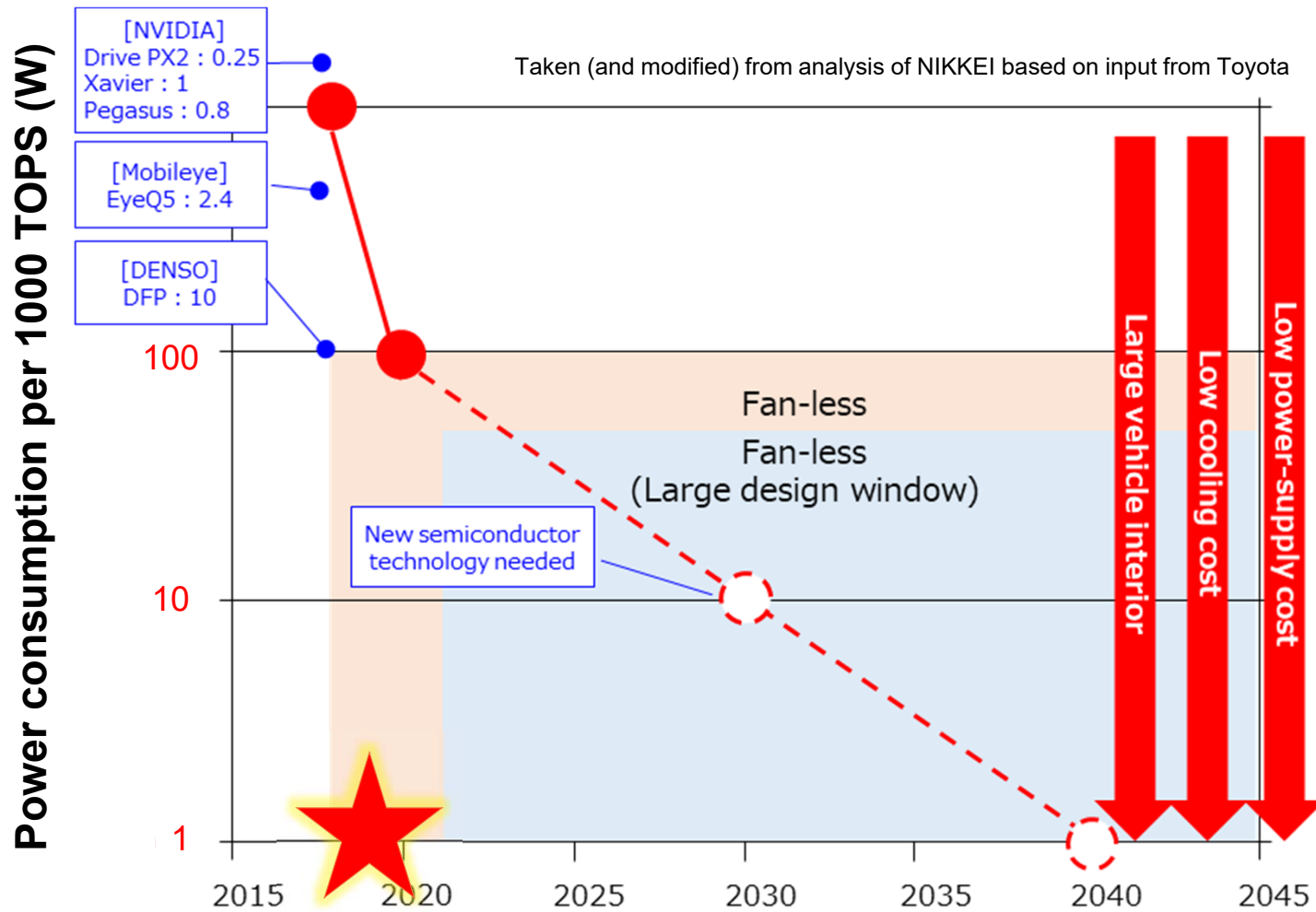
Process	90nm-CMOS/70nm-MTJ
Core Size	0.3mm x 0.9mm
Frequency	20 MHz
Supply Voltage	0.9 V
Average Operation Power	600 μW (30 μW/MHz)
Throughput (cycles/vector)	16

Y. Ma *et al.* Jpn. J. Appl. Phys. **55** 04EF15 (2016).

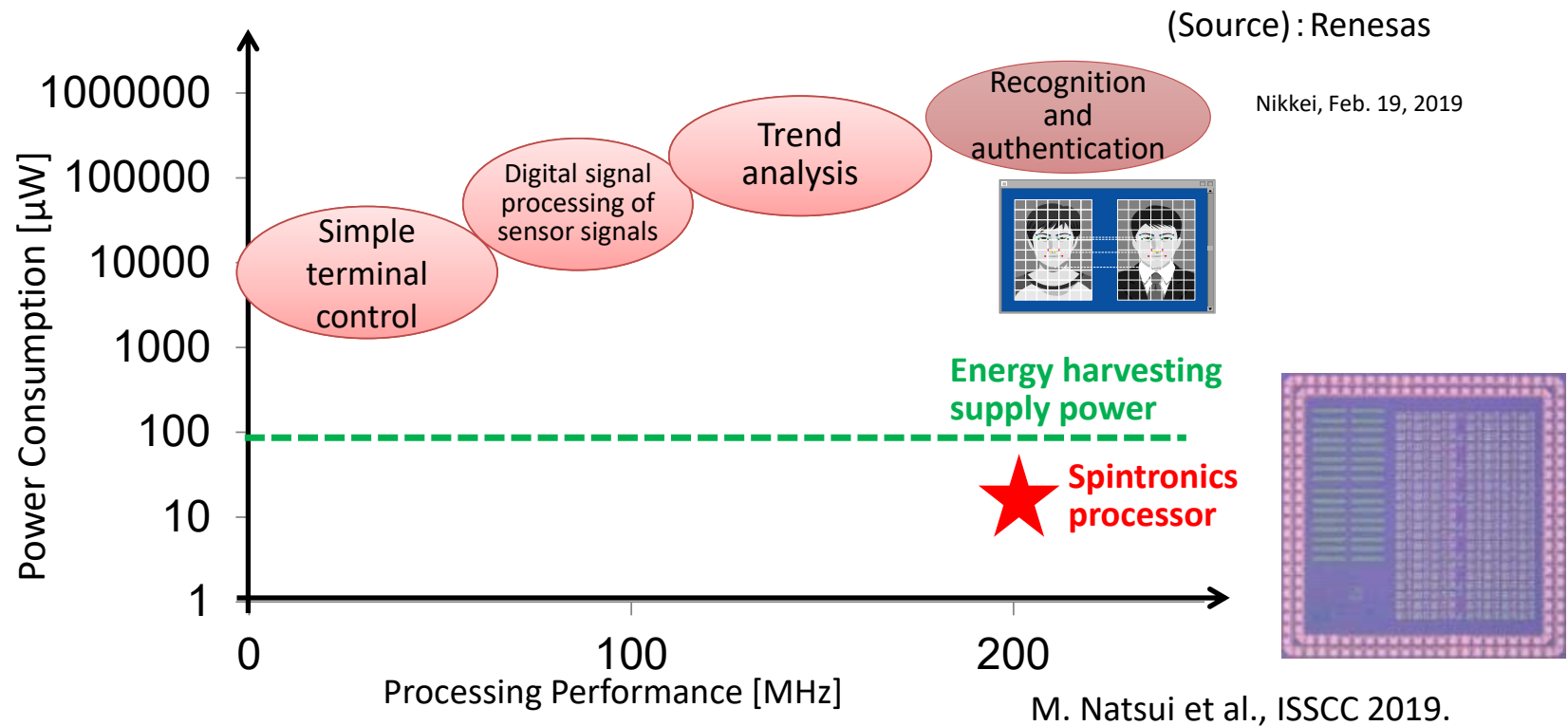
Tensor Processing Unit (TPU) @Google

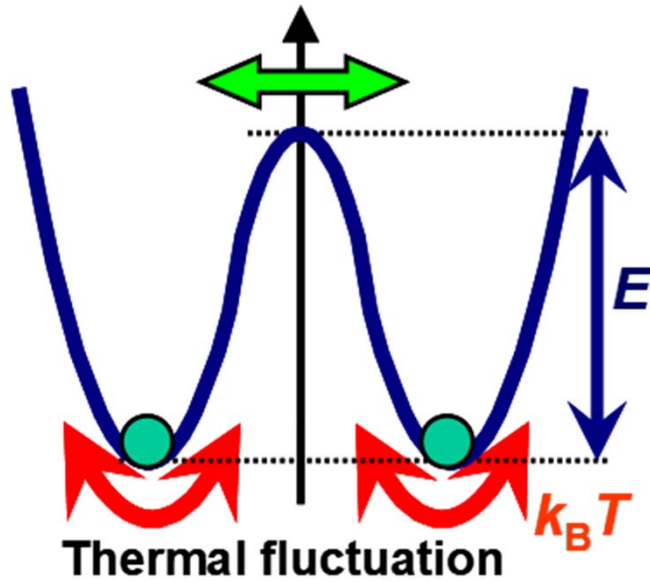
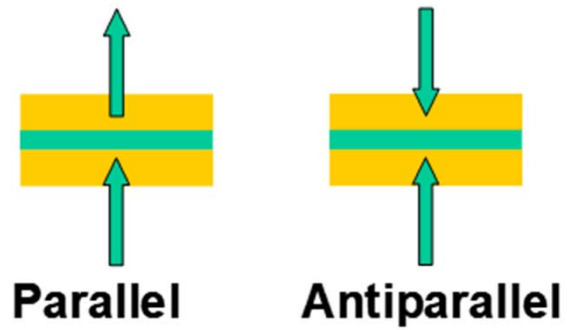
- ◆ Process: 28 nm CMOS
- ◆ Frequency: 700 MHz
- ◆ Operation Power: 28~40W
(40~57mW/MHz)

AI chip requirement for autonomous driving

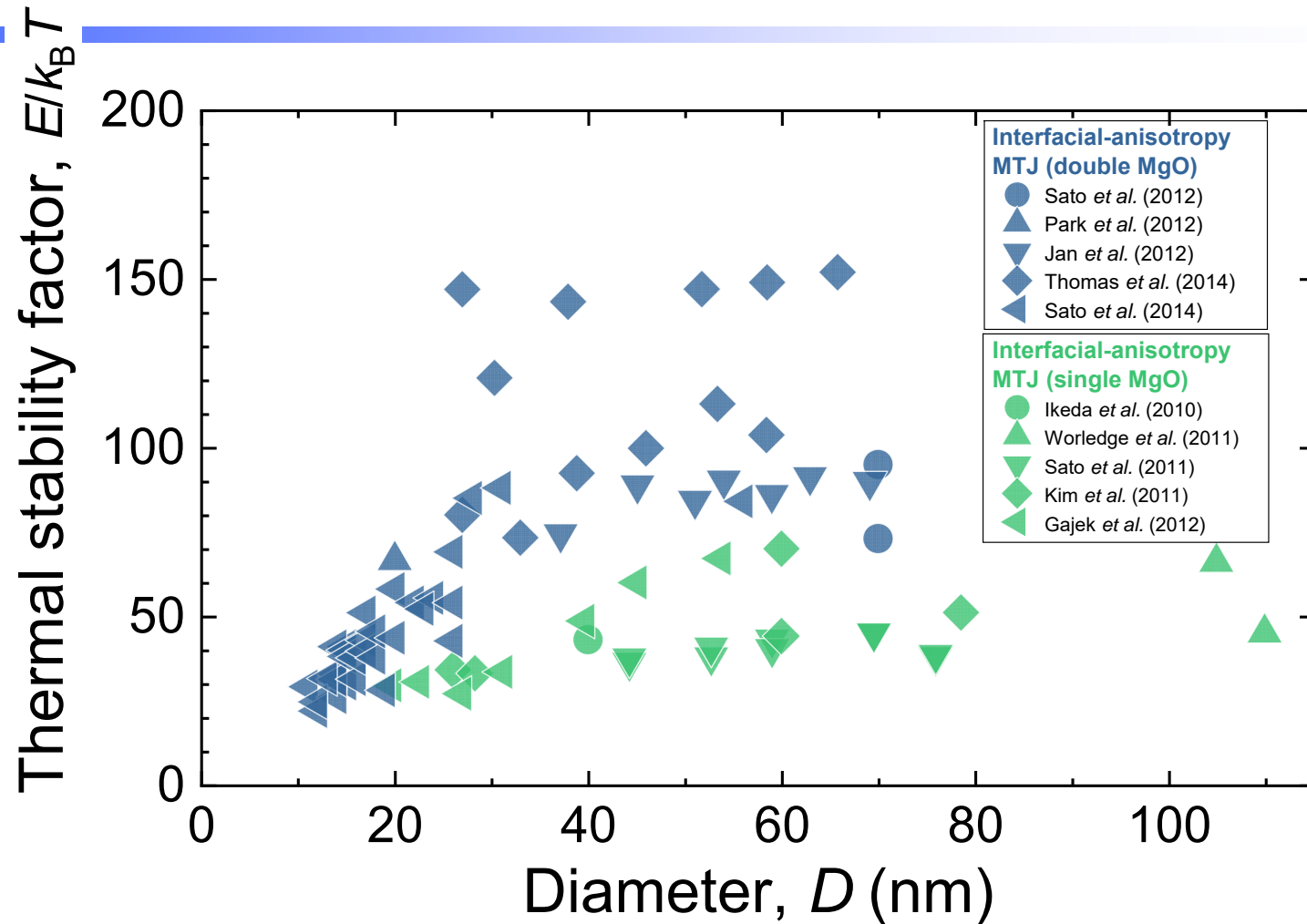


Ultralow energy consumption processor





$$E = -\frac{M_S^2}{2\mu_0} V + K_i S$$

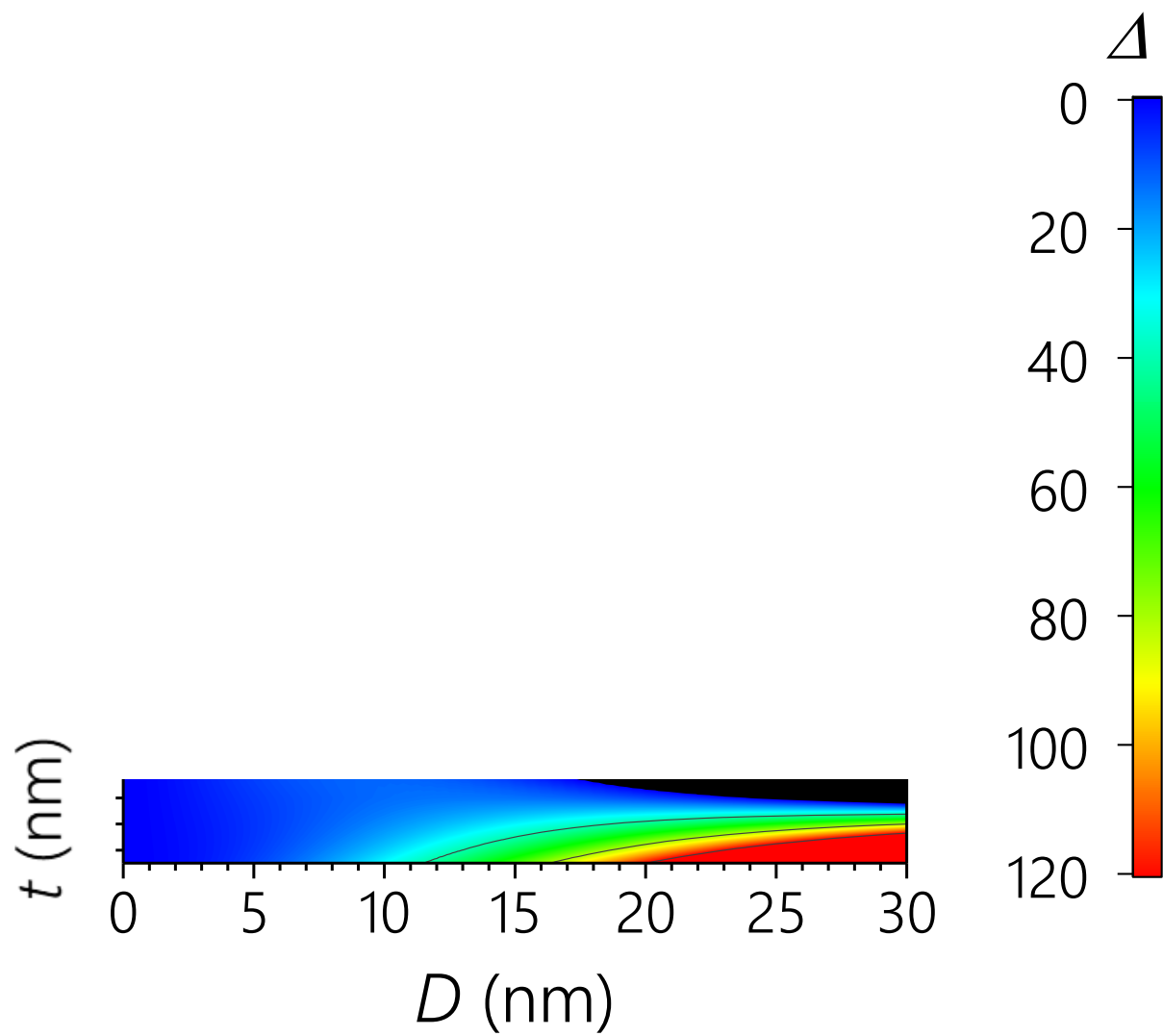


After B. Jinnai *et al.*, Appl. Phys. Lett. **116**, 160501 (2020).

Physical Vapor Deposition System (300mm)



http://www.tel.co.jp/news/2014/1201_001.htm

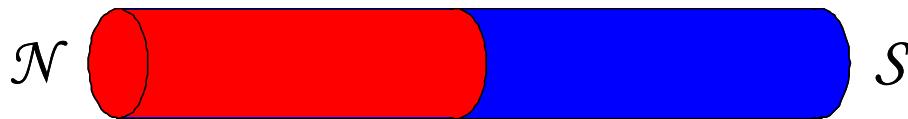


Energy barrier E

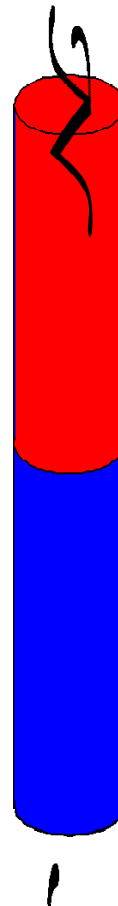
$$E = N \frac{M_S^2}{2\mu_0} V$$

shape anisotropy

N : demagnetization factor



$N = 1$ (perpendicular)



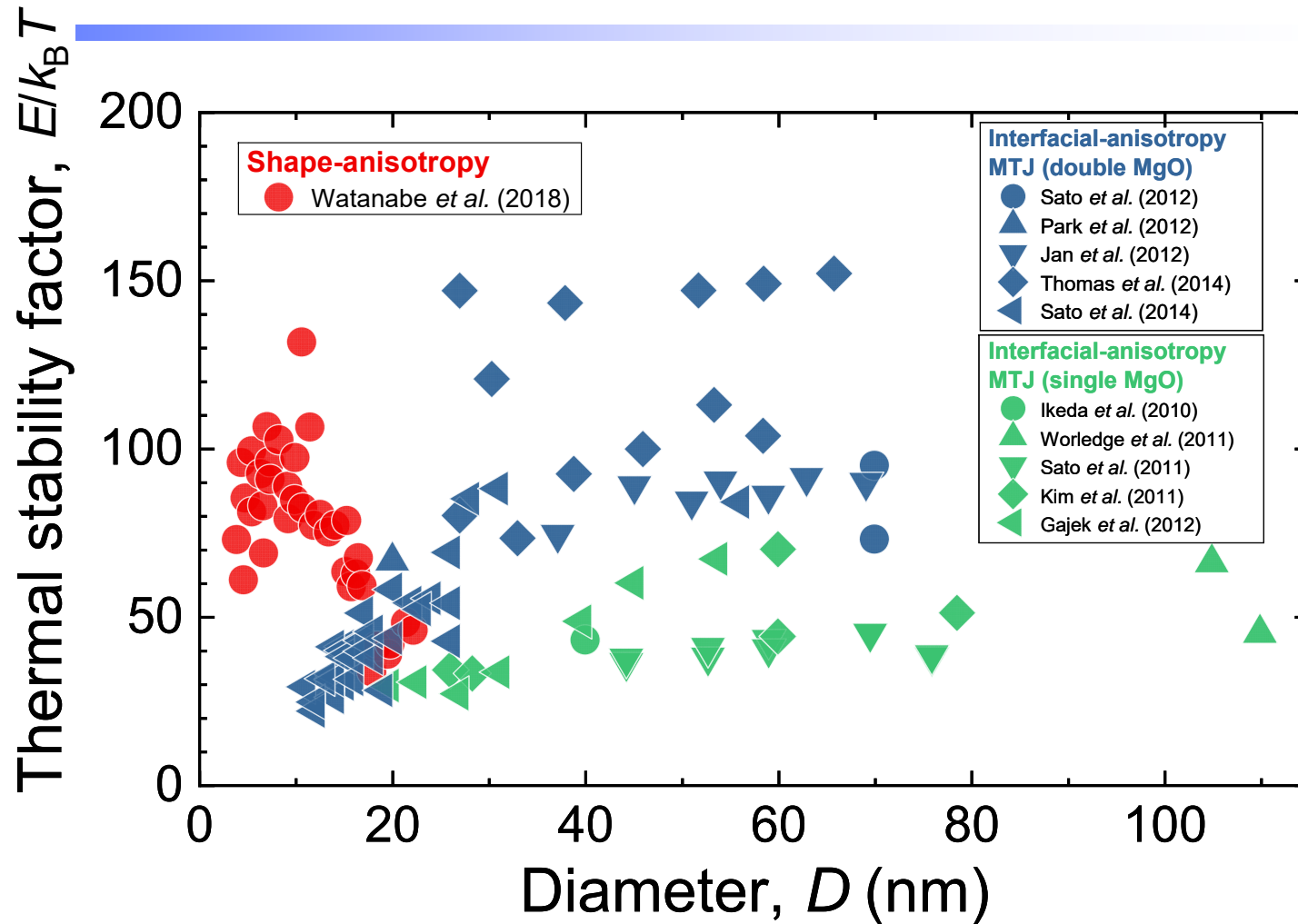
$$+ K_i S$$

interface anisotropy

V : volume
 S : area

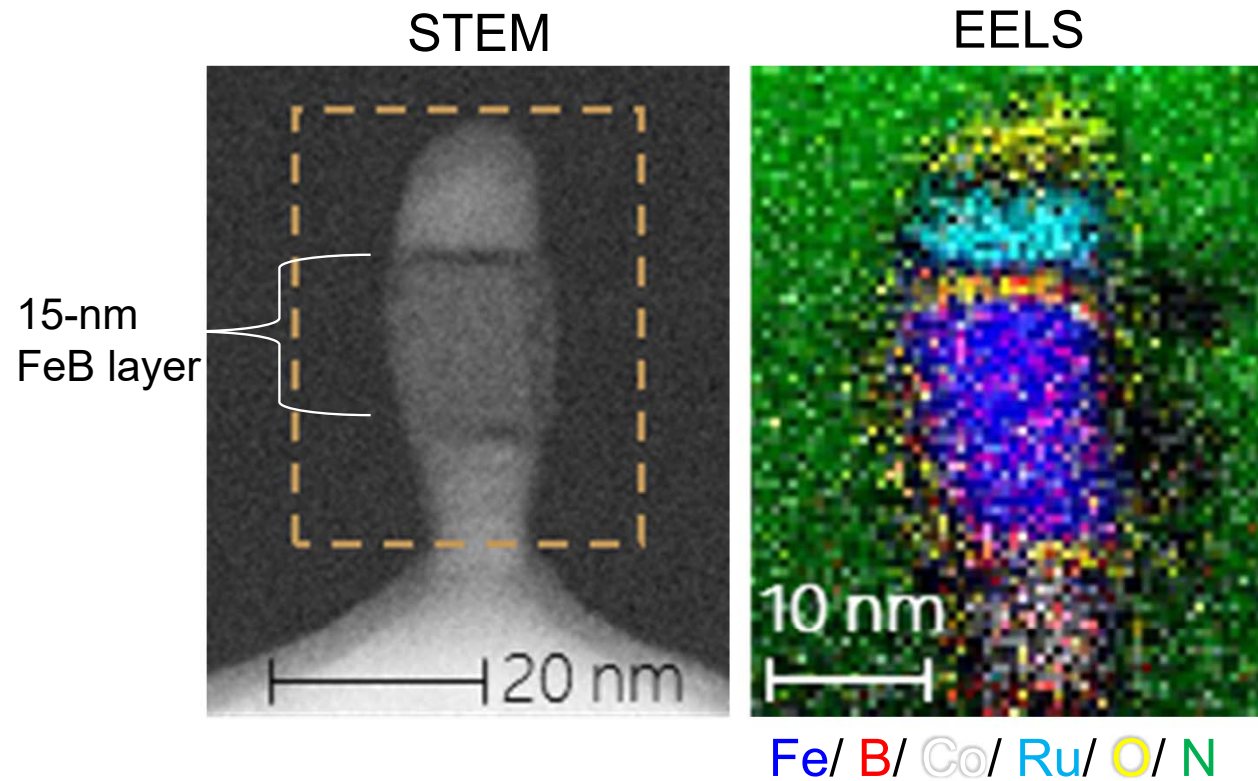
$$K_i > 0$$

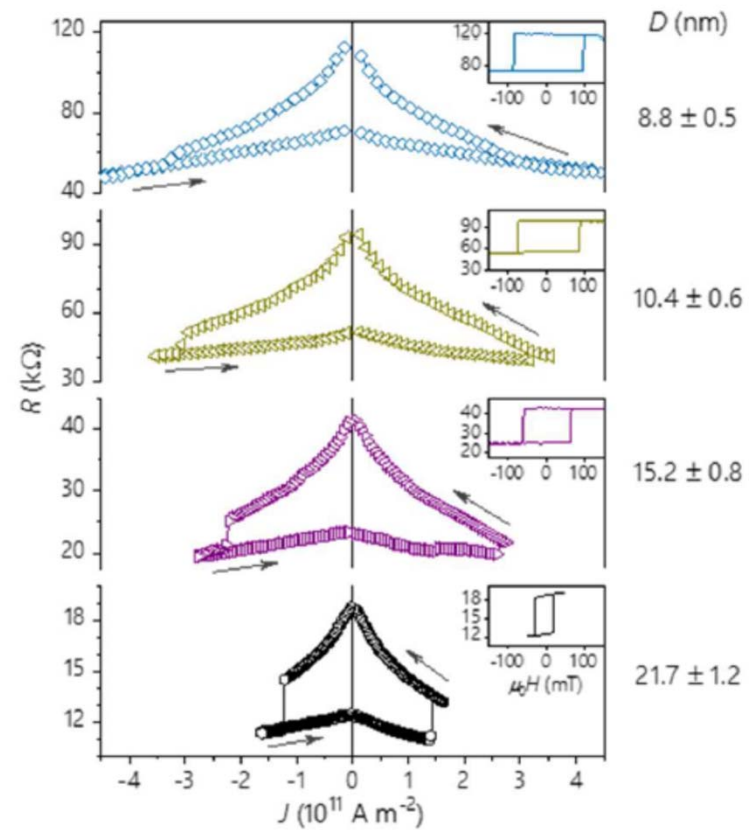
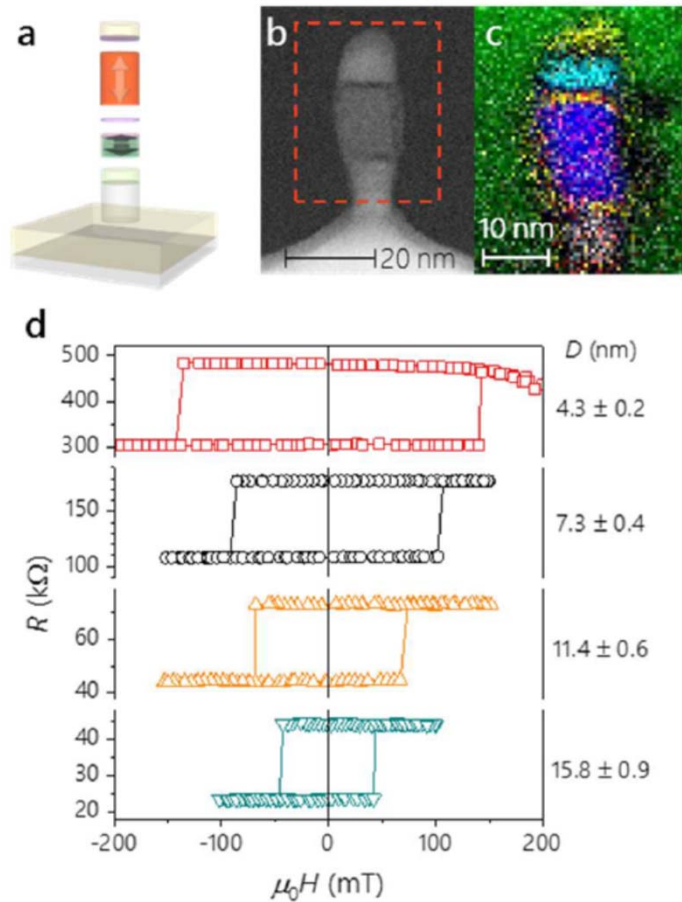
(perpendicular)



After B. Jinnai *et al.*, Appl. Phys. Lett. **116**, 160501 (2020).

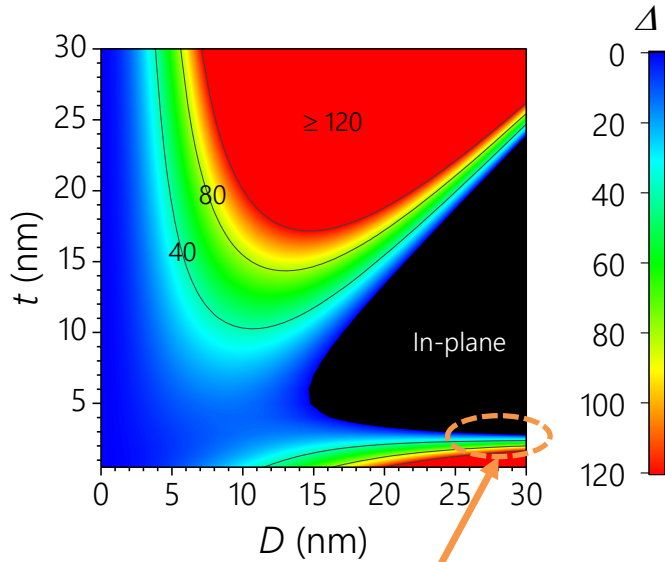
The shape-anisotropy MTJ



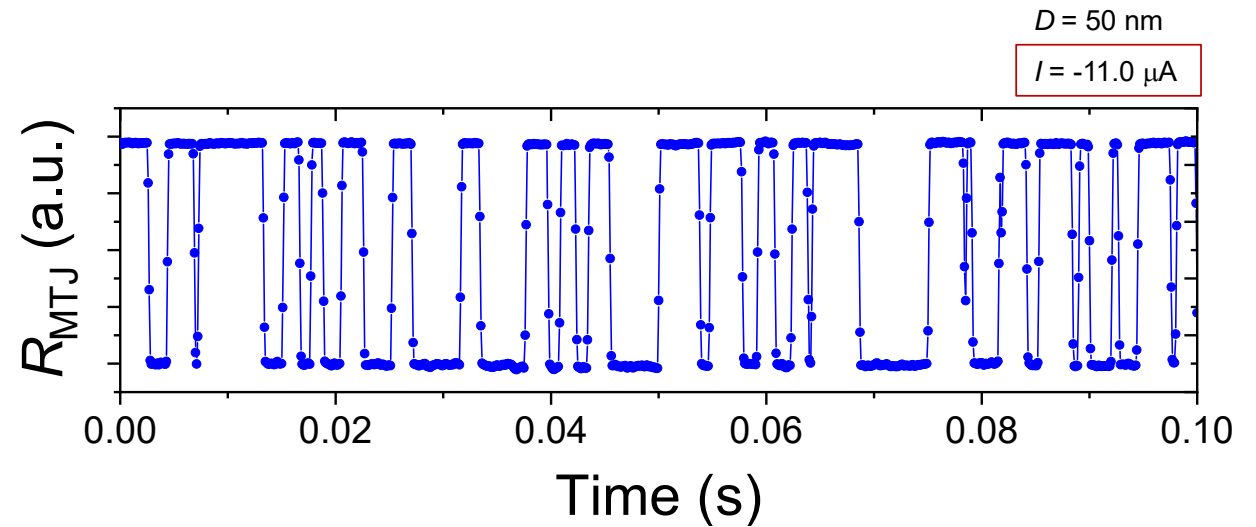
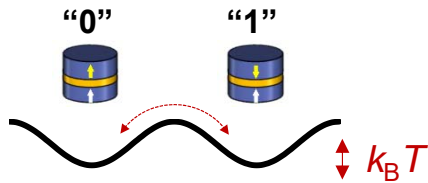


→ K. Watanabe et al., *Nature Comm.* **9**, 663 (2018)
 See also, N. Perrissin et al., *Nanoscale* **10**, 12187 (2018)

Magnetic tunnel junction : $E/k_B T < 20$

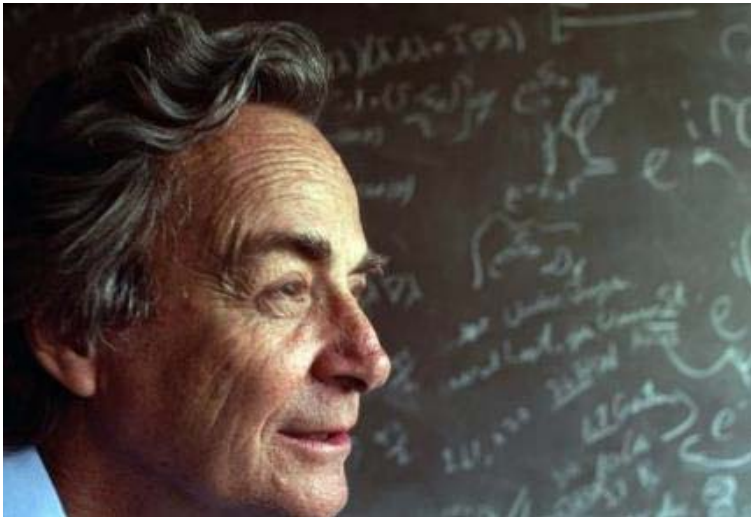


Thermally unstable
(Stochastic)



Lecture by Richard Feynman (1981)

“Simulating Physics with Computers”



<https://www.nature.com/articles/d41586-019-02781-4>

Physics of Computation Conference
at MIT
on May 6-8, 1981

“If you want to make a simulation of nature, you’d better make it quantum mechanical, ...”



Quantum computing

“...the other way to simulate a probabilistic nature is by a computer which itself is probabilistic, ...”



Probabilistic computing

“Simulating Physics with Computers”, International Journal of Theoretical Physics **21**, 467-488 (1982).

Probabilistic computing

- Boltzmann distribution

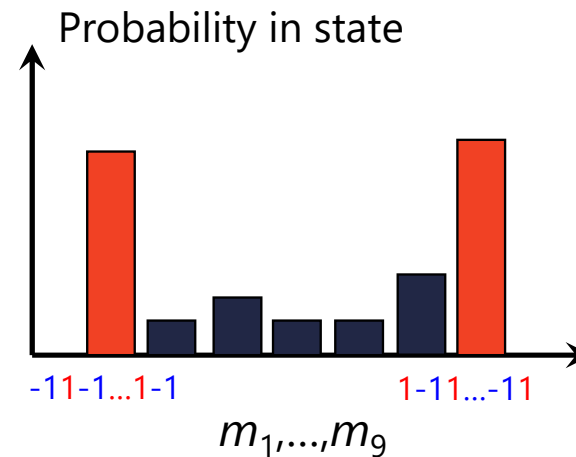
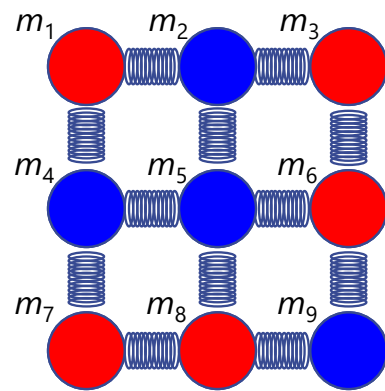
$$P(E, T) = \frac{1}{Z} \exp \left[-\frac{E(\Gamma)}{k_B T} \right]$$

The lowest energy state is most-frequently observed.
→ Probabilistic computing

Procedure of probabilistic computing

1. Define an **energy (cost function)** for each given problem.
2. Mapping the cost function to a **physical system with probabilistic nature (stochastic neurons)**.
3. Acquiring **statistics**.
4. The most frequent state is the “answer”.

$$E = - \sum J_{ij} m_i m_j$$



What we did ...

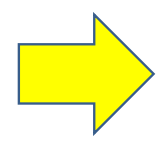


Controllable
stochasticity

Sigmoidal
response

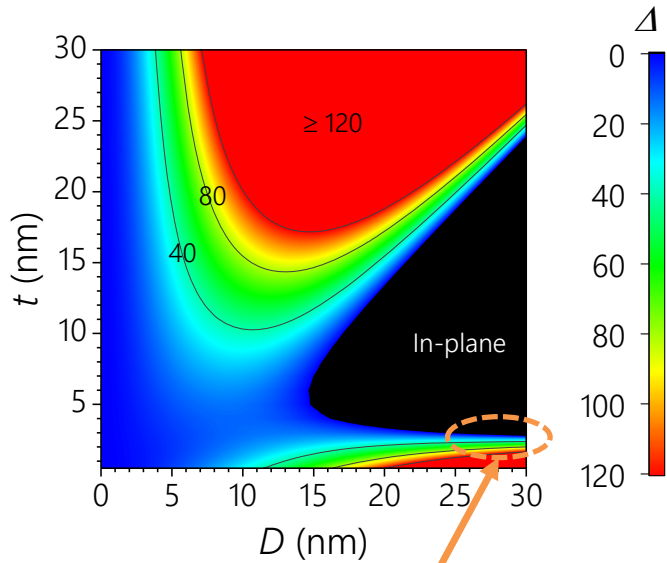
Connected
by synaptic
weight logic

Mapping
cost function
to system

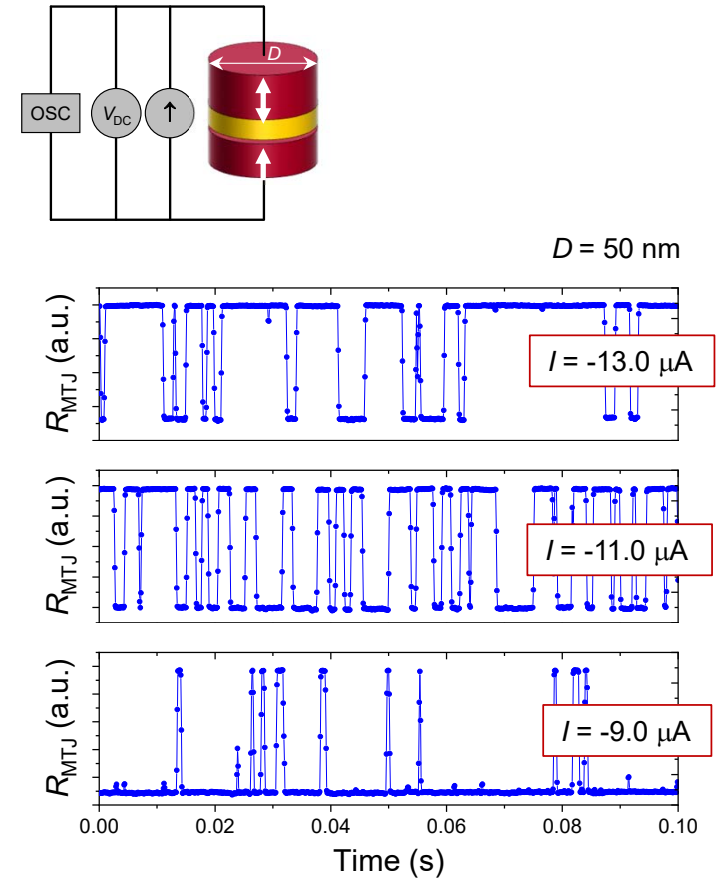
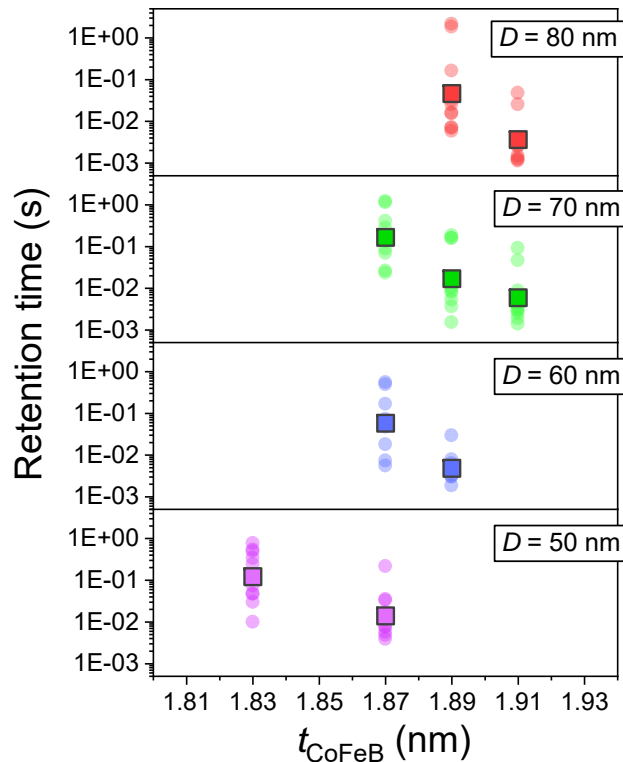
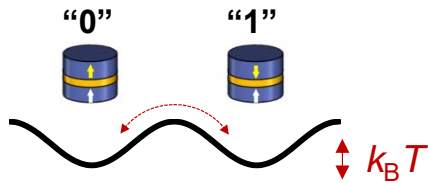


Integer factorization
(illustrative example of optimization)

Stochastic magnetic tunnel junction



Thermally unstable (Stochastic)



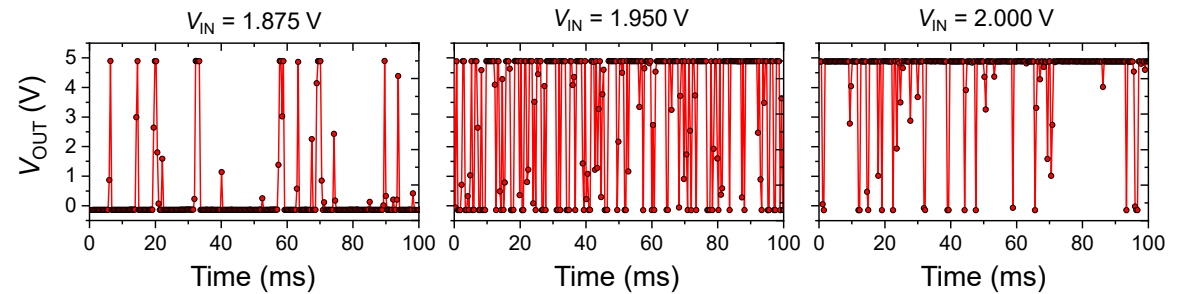
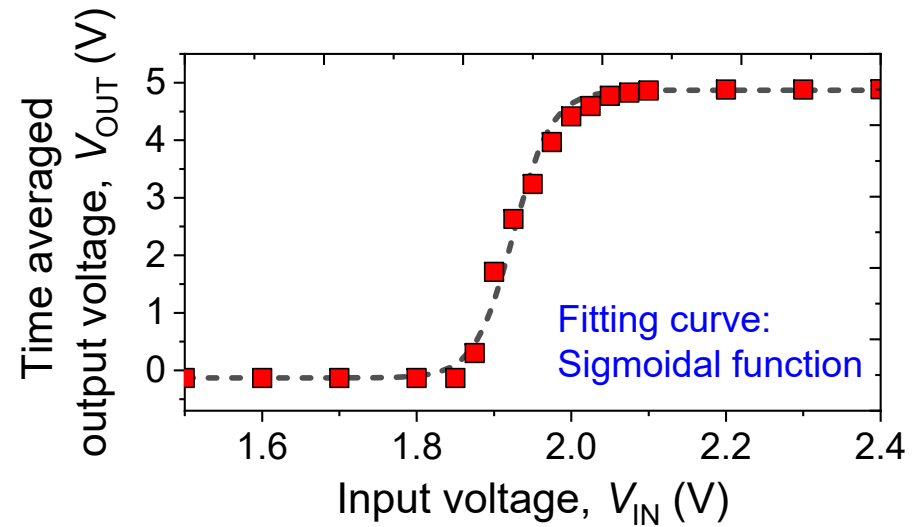
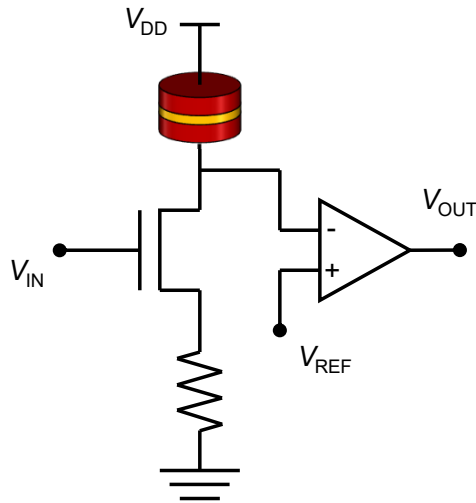
Probabilistic bit (p-bit)

Device

Bit

Circuit

Algorithm



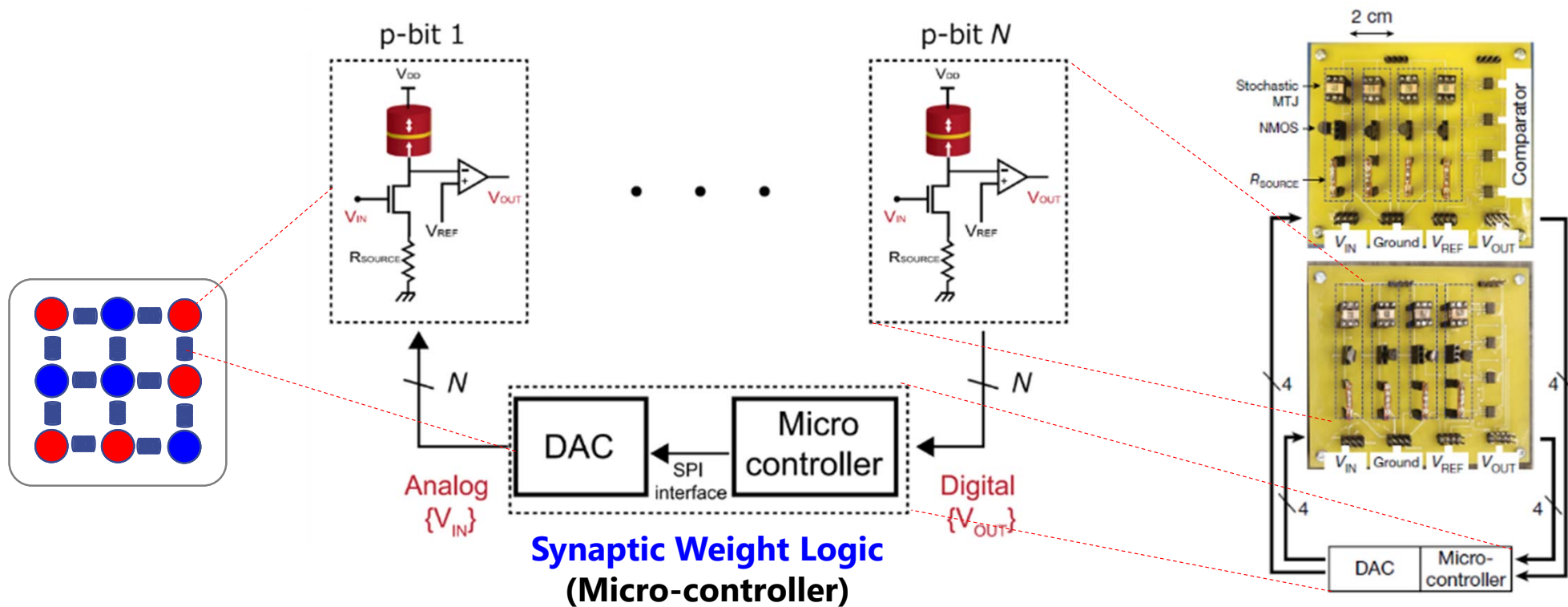
Probabilistic circuit (p-circuit)

Device

Bit

Circuit

Algorithm



Cost function for integer factorization

Device

Bit

Circuit

Algorithm

$$E = (XY - F)^2 \quad \begin{cases} X = 1 + 2x_1 + 4x_2 + 8x_3 + \dots \\ Y = 1 + 2y_1 + 4y_2 + 8y_3 + \dots \end{cases}$$

◆ Example) Factorizing 35 (= F) by 4 bits (x_1, x_2, y_1, y_2)

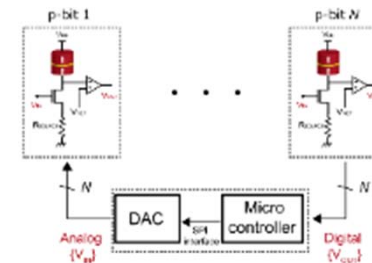
coefficients are rounded off to have one significant digit.

$$E = -0.3x_1 - 0.7x_2 - 0.3y_1 - 0.7y_2 - x_2y_1 - 1.4x_2y_2 - 0.6x_1y_1 - x_1y_2 + \underline{0.3x_1y_1y_2} + \underline{x_2y_1y_2} + \underline{0.3x_1x_2y_1} + \underline{x_1x_2y_2} + \underline{0.7x_1x_2y_1y_2}$$

3-body interaction

4-body interaction

$$\begin{cases} I_{x_1} = -\frac{\partial E}{\partial x_1} = 0.3 + 0.6y_1 + 1.0y_2 - 0.3y_1y_2 - 0.3x_2y_1 - 1.0x_2y_2 - 0.7y_1x_2y_2 \\ I_{x_2} = -\frac{\partial E}{\partial x_2} = 0.7 + 1.0y_1 + 1.4y_2 - 1.0y_1y_2 - 0.3x_1y_1 - 1.0x_1y_2 - 0.7x_1y_1y_2 \\ I_{y_1} = -\frac{\partial E}{\partial y_1} = 0.3 + 0.6x_1 + 1.0x_2 - 0.3x_1y_2 - 1.0x_2y_2 - 0.3x_1x_2 - 0.7x_1x_2y_2 \\ I_{y_2} = -\frac{\partial E}{\partial y_2} = 0.7 + 1.0x_1 + 1.4x_2 - 0.3y_1x_1 - 1.0y_1x_2 - 1.0x_1x_2 - 0.7x_1x_2y_1 \end{cases}$$



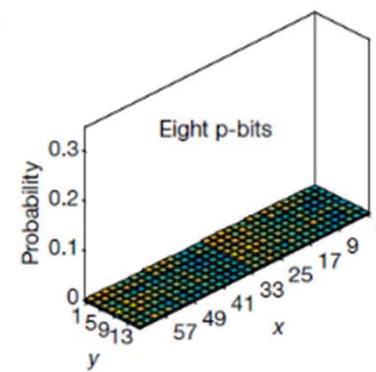
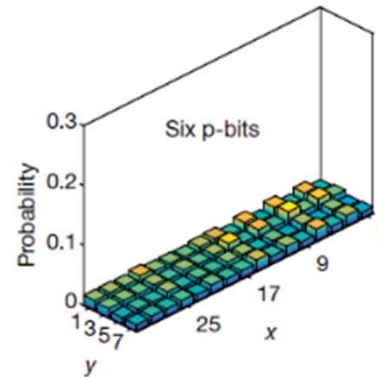
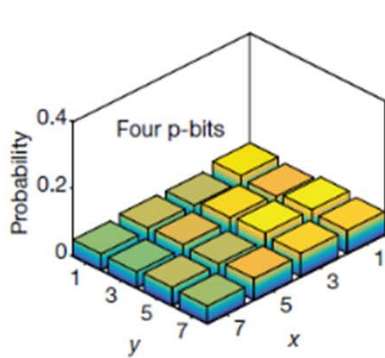
Results of integer factorization

$F =$

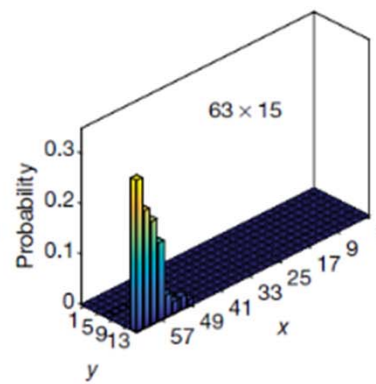
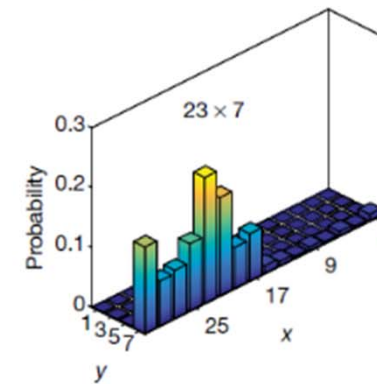
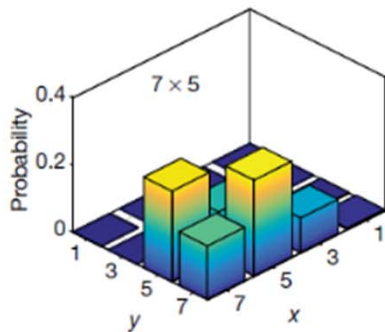
35

161

945



← Uncorrelated



← Correlated

$X \times Y =$

7×5

23×7

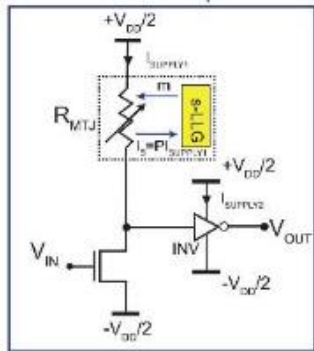
63×15

Comparison with quantum annealing machine

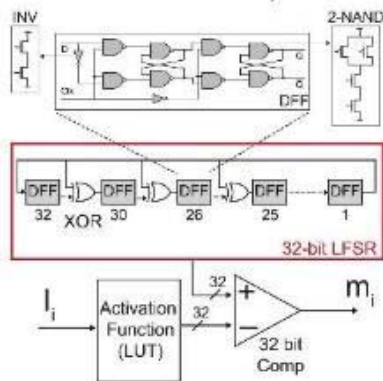
- Room temperature
- Manufacturable at the Mb-Gb level (STT-MRAM)
- Can implement many-body interactions easily
- No quantum supremacy

Comparison with CMOS-based simulated annealing

◆ MTJ-based p-bit

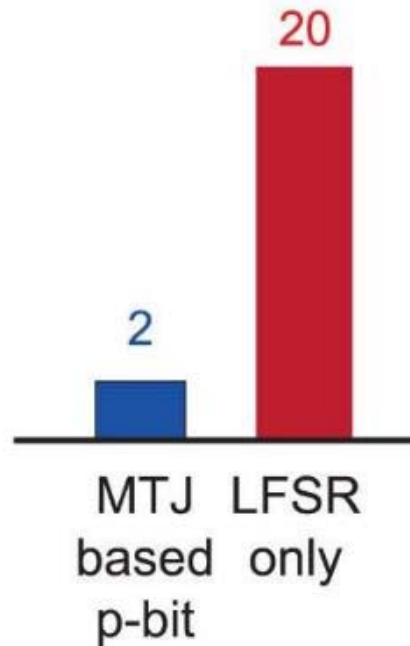


◆ Digital CMOS-based p-bit



LFSR: Linear-feedback shift register
LUT: Look-up table

Energy per random bit (fJ)



Transistor Count (#)

